

Application No. 10/652,007

Amendment dated September 12, 2005

Reply to Office Action of June 13, 2005 and Advisory Action of August 23, 2005

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1-36 (Cancelled)

37. (Previously presented) The low dielectric constant fluorine and carbon-doped silicon oxide dielectric material of claim 50 wherein at least one of the carbon atoms participating in said C-C bond is also bonded to at least one fluorine atom.

38. (Cancelled)

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39. (Currently Amended) A low dielectric constant fluorine and carbon-doped silicon oxide dielectric material for use in an integrated circuit structure comprising the reaction product of an oxidizing agent and one or more silanes comprising one or more organofluoro silanes having the formula $\text{SiR}_1\text{R}_2\text{R}_3\text{R}_4$, wherein:

- (a) R_1 is selected from the group consisting of H, a 3 to 5 carbon organo moiety, and an oxyorgano moiety;
- (b) R_2 is an organofluoro moiety; and
- (c) R_3 and R_4 are independently selected from the group consisting of the same or different leaving group, the same or different organofluoro moiety, and the same or different organofluoro moiety, and the same or different $((\text{L})\text{Si}(\text{R}_5)(\text{R}_6))_n(\text{R}_7)$; wherein n ranges from 1 to 5; L is O or $(\text{C}(\text{R}_8)_2)_m$; m ranges from 1 to 4; each of the n R_5 's and n R_6 's is independently selected from the group consisting of the same or different leaving group and the same or different organofluoro moiety; R_7 is selected from the group consisting of a leaving group and an organofluoro moiety; and each of the $2n^*m$ or fewer R_8 's is selected from the group consisting of F and the same or different organofluoro moiety;

and further characterized by:

- (d) each silicon atom is bonded to at least 1 oxygen atom;
- (e) silicon atoms bonded to carbon atoms;
- (f) at least 1 carbon atom bonded to 1 to 2 fluorine atoms; and;
- (g) the presence of at least 1 C-C bond.

40. (Cancelled)

41. (Previously Presented) The low dielectric constant fluorine and carbon-doped silicon oxide dielectric material of claim 39 wherein said oxidizing agent comprises hydrogen peroxide.

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42. (Previously Presented) The low dielectric constant fluorine and carbon-doped silicon oxide dielectric material of claim 39 wherein said R₁ comprises hydrogen.

43. (Previously Presented) The low dielectric constant fluorine and carbon-doped silicon oxide dielectric material of claim 39 wherein said R₂ comprises an organofluoro moiety containing CF₃.

44. (Previously Presented) The low dielectric constant fluorine and carbon-doped silicon oxide dielectric material of claim 39 wherein said R₂ consists essentially of C and F atoms.

45. Previously Presented) The low dielectric constant fluorine and carbon-doped silicon oxide dielectric material of claim 39 wherein said R₂ consists essentially of C and F atoms alone.

46. (Currently Amended) The low dielectric constant fluorine and carbon-doped silicon oxide dielectric material of claim 39 wherein said R₂ comprises consists essentially of C and F atoms and R₃ consists essentially of an alkyl.

47. (Previously Presented) The low dielectric constant fluorine and carbon-doped silicon oxide dielectric material of claim 39 wherein said R₃ contains CH₃ moieties.

48. (Previously Presented) The low dielectric constant fluorine and carbon-doped silicon oxide dielectric material of claim 39 wherein said R₄ comprises a leaving group.

49. (Previously Presented) The low dielectric constant fluorine and carbon-doped silicon oxide dielectric material of claim 39 wherein said R₄ comprises hydrogen.

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50. (Previously Presented) A low dielectric constant fluorine and carbon-doped silicon oxide dielectric material for use in an integrated circuit structure and further characterized by:

- (a) each silicon atom is bonded to at least 1 oxygen atom ;
- (b) silicon atoms bonded to carbon atoms;
- (c) at least 1 carbon atom bonded to 1 to 2 fluorine atoms; and
- d) the presence of at least 1 C-C bond.

51. (Cancelled)